## Adjustable ECR Broad Beam Ion Sources

EC/A 125



## **Key Design Features**

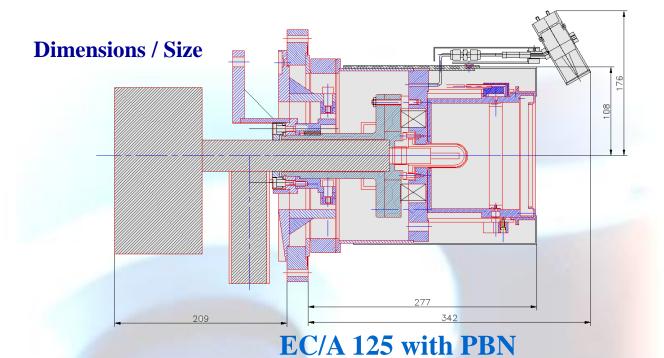
- → Filamentfree source operation based on a simple, compact microwave power coupling
- → Permanent magnets for use of the Electron Cyclotron Resonance (ECR)
- → Functional ceramics for easy and quick maintenance
- Special grid insulation and adjustment system

## **Advantages**

- → Fully noble gas, and oxygen; restricted for reactive gases
- Grid systems from different shape and material for optimum process adaptation
- Minimum maintenance and long lifetime, maintenance cycles over 300 h
- → Mechanical adjustment system by universal joint (10 grd in each direction)

The best solution for filament free ion beam processing on large scale!





## **Technical Specification**

	EC/A 125	<u>EC/F 125</u>
Type:	Flange mounted adjustable ECR ion source with multiapertur extraction grids	Flange mounted ECR ion source with multiapertur extraction grids
Source materials:	Discharge lining: Al <sub>2</sub> O <sub>3</sub>	
	Grids: Graphite or Molybdenum	
	Vacuum separation of the microwave antenna: SiO <sub>2</sub> cup	
	Permanent magnets: NdFeB	
	Housing: Stainless steel	
	Magnetic shield: Ni coated steel	
Grid types:	2 or 3 grid system 2 standard systems with different focusing length	
Size:	Insertion depth: 280 mm (without PBN) Diameter: 220 mm (without PBN)	Insertion depth: 135 mm (without PBN Diameter: 220 mm (without PBN)
Weight:	~14.5 kg	~11.5 kg
Flange:	DN 250	DN 200
Microwave power:	~125 to 400 W at 2.45 GHz	
Ion current:	Maximum 180 mA (Dependent on grid type and operation condition)	
Ion energy:	~100 to 2000 eV	
Accelerator voltage:	0 to -1000 V	
Process gases:	Noble gases, N <sub>2</sub> (No restrictions) O <sub>2</sub> ,and Halogen containing gases (Grid lifetime reduced)	
Gas flow:	5 to 20 sccm, Fitting: 1/8" Swagelock	
Cooling water:	1.5 l/minFitting: 6 mm Swagelock	